## PATENT APPLICATION

## IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re the Application of

Hideki KOMATSUDA et al.

Group Art Unit: 2882

Application No.: 09/396,582

Examiner:

C. Church

Filed: September 15, 1999

Docket No.: 105203

For:

EXPOSURE APPARATUS AND EXPOSURE METHOD USING SAME

## INFORMATION DISCLOSURE STATEMENT

Director of the U.S. Patent and Trademark Office Washington, D.C. 20231

Sir:

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Pursuant to 37 CFR §1.56, the attention of the Patent and Trademark Office is hereby directed to the reference(s) listed on the attached PTO-1449. Unless otherwise indicated herein, one copy of each reference is attached. It is respectfully requested that the information be expressly considered during the prosecution of this application, and that the reference(s) be made of record therein and appear among the "References Cited" on any patent to issue therefrom.

1. This Information Disclosure Statement is being filed with a Request for Continued Examination. No certification or fee is required.

2. The references were cited in a counterpart foreign application. An English language version of the foreign search report is attached for the Examiner's information.

Respectfully submitted,

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Date: June 13, 2001

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